# Novel IrO<sub>x</sub> nanodots based capacitive pH sensor

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# 1. Introduction

In recent years, EIS structure has drawn major attention among the various semiconductor based biosensors such as ISFET, EIS, and LAPS etc. because of its simplicity in layout, label free detection, easy and cost effective fabrication. Nanoparticles have shown their potential as major diagnostic tool in biological detection because of their unique size dependent electronic, optical and spectroscopic properties due to their small size and comparative high surface area [1]. Very few studies have been reported towards nanoparticles modified EIS structures. Various nanostructure metal oxides have been used as transducers for biosensor such as ZnO, ZrO<sub>x</sub>, TiO<sub>x</sub> etc. which have shown their functional biocompatibility, non-toxic and high catalytic efficiency [2]. Nanostructured iridium oxide (IrOx) has attracted more attention due to its promising properties such as chemical stability and good adsorption properties for the biomolecules immobilization. IrOx shows good response to charge variation at interface because it maintains high charge transfer ratio [3]. As iridium oxide nanostructure are compatible with intracellular material, IrOx based sensors has been developed to detect biochemical such as enzymes, antibodies and hybridized DNA. Presence of IrO<sub>x</sub> nanostructure facilitates the control of the morphology and wettability of the surface which ultimately results in the enhanced sensitivity, single molecule detection and significant reduction in analyte concentration. Recently, W. D. Huang et al. [4] reported the IrO<sub>x</sub> film as an electrochemical pH sensor [4], however IrO<sub>x</sub> nanodots (NDs) modified EIS structure as capacitive pH sensor has not been reported yet. This novel IrOx-NDs based pH sensor shows a promising sensing performance with a near-Nernstian response in sensitivity repeatedly and reversibly in between 46.4-52.4 mV/pH in the pH range between 2 and 12 at 25°C.

### 2. Experiment

p-Type Si (100) substrate was cleaned by the RCA process to remove native oxide from the surface. After RCA cleaning, a 40 nm-thick SiO<sub>2</sub> layer was grown as an insulating layer by dry oxidation process at 1000°C. Then, the IrO<sub>x</sub> nano-layer with a nominal thickness of ~ 1nm was deposited by reactive rf sputtering. The Ir target was used for the deposition of IrO<sub>x</sub> layer. To fabricate the EIS chip, first a 300 nm-thick Al film was deposited on the back side of the samples after removing the back side oxide using buffer oxide etching solution (BOE). The sensing membrane area was defined by standard photolithography process using a negative photoresist-SU8. Then, EIS devices were attached on a printed circuit board having copper lines. Then, an epoxy layer was used to encapsulate the EIS structure and the copper line. A schematic view of the major fabrication steps of IrO<sub>x</sub>-NDs modified EIS sensor are shown in Fig. 1. The capacitance-voltage (C-V) measurements were performed with Agilent 4284A by substrate bias through an Ag/AgCl reference electrode.

# 3. Results and discussion

Figs.1 (a) - (d) show the schematic view of fabrication process as well as the physical characterization of the iridium oxide modified EIS sensor. After IrOx NDs deposition on SiO2 surface, their distribution was confirmed by STEM and HRTEM images, as shown in Fig. 1(c). High density  $(1.18 \times 10^{13} / \text{cm}^2)$  of self-assembled IrO<sub>x</sub>-NDs is clearly observed from the large view of STEM images. Size of IrOx NDs is in range of 1.5nm to 2.5nm as calculated from the high-resolution TEM image. A schematic view of EIS sensor chip is shown in Fig. 1(d). Charge trapping properties of IrO<sub>x</sub>-NDs in an IrO<sub>x</sub>/Al<sub>2</sub>O<sub>3</sub>/IrO<sub>x</sub>-NDs/Al<sub>2</sub>O<sub>3</sub>/n-Si structure are observed, which prove

# the available Ir-O dangling bonds on the surface of IrO<sub>x</sub>-NDs (Fig. 2).

Presence of  $IrO_x$ -NDs on SiO<sub>2</sub> layer is confirmed with EDX analysis, as shown in Figs. 3 & 4. As  $IrO_x$  –NDs deposited on SiO<sub>2</sub> surface using RF sputtering in presence of equal ratio of argon and oxygen, two oxidation states of  $IrO_x$  was expected on SiO<sub>2</sub> surface that was confirmed with the XPS analysis (Figs. 5 & 6). pH sensing behavior of bare EIS sensor and  $IrO_x$ -NDs modified EIS sensor was characterized by typical C-V measurements at different pH buffer solutions, as shown in Figs. 7 & 8. Sensitivity of EIS sensor is calculated from the linear depletion region of the C-V curve. A respective shift in flat band is observed according to the different concentration of hydrogen ions in buffer solutions. Sensitivity of EIS sensor is calculated using the following equation:-

$$Sensitivity = \frac{\Delta V_{fb}}{\Delta p H}$$
[1]

IrO<sub>x</sub>-NDs modified EIS sensor showing comparatively high sensitivity for hydrogen ions as compared to bare  $SiO_2$  EIS sensor. This behavior shows the high charge transfer properties of IrO<sub>x</sub>. Mechanism of the surface reaction of IrO<sub>x</sub>-NDs in different pH environment can be explained by the reactions [5] as follows:-

$$Ir_2O_3 + 6H^+ + 6e^- \leftrightarrow 2Ir + 3H_2O$$
<sup>[2]</sup>

$$IrO_2 + 4H^+ + 4e^- \leftrightarrow Ir + 2H_2O$$
<sup>[3]</sup>

$$2IrO_2 + 2H^+ + 2e^- \leftrightarrow Ir_2O_3 + H_2O$$
<sup>[4]</sup>

At high acidic conditions, more reduction takes place at  $IrO_x$  surface that leads to band bending ultimately work function of  $IrO_x$  and result in high flat band voltage compared to high pH buffer solution.  $IrO_x$ modified EIS sensor showing high average sensitivity of 48.4mV/pH with very good linearity of 99.94% while bare SiO<sub>2</sub> showing sensitivity of 33-35mV/pH with linearity of 98.35% (Fig. 9). Standard error measurement of three  $IrO_x$  EIS sensor shows less deviation and high repeatability of EIS sensor device (Fig. 10). Fig. 11 shows concap response of  $IrO_x$ -NDs modified EIS sensor that proves the stability and confirms the repeatability of  $IrO_x$  NDs modified EIS sensor.

# 4. Conclusion

A novel IrO<sub>x</sub>-NDs based capacitive pH sensor chip has been fabricated and characterized for the first time. IrO<sub>x</sub>-NDs modified EIS sensors showing comparatively high sensitivity of 48.8mV/pH with linearity of 99.94% (with a near-Nernstian response in sensitivity) than that of the bare SiO<sub>2</sub> sensor showing sensitivity of ~ 35mV/pH with the linearity of 98.35%. Easy as-deposited and self-assembled IrO<sub>x</sub>-NDs based Ph sensor fabrication, good repeatability and high stability paves a way in future biosensor applications.

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#### References

A.N. Shipway, et al. Chem. Phys. Chem., vol. 1, p. 18 (2000). [2] P.R. Solanki, et al., NPG Asia Material, vol. 3(1), p. 17 (2011). [3] V.L. Venkatraman, et. al. Biosens. & Bioelectr. vol. 24, p.3078 (2009). [4] Wen-Ding Huang, et. al. Sensors and Actuators: A, vol. 169, p. 1, (2011). [5] M. Pourbaix, Atlas of electrochemical equilibria in aqueous solutions, National Association of Corrosion Engineers p. 374, 1974.



Fig. 1 Schematic view of the fabrication process of iridium oxide (IrO<sub>x</sub>) nanodots (NDs) modified EIS sensor chip. (a) 40nm SiO<sub>2</sub> deposition with thermal oxidation, (b) IrO<sub>x</sub> NDs deposition using RF sputtering technique, (c) Plane view STEM/HRTEM images to calculate size and density of NDs distribution, and (d) schematic view of EIS sensor chip. A high density of  $1.18 \times 10^{13}$ /cm<sup>2</sup> is observed for as-deposited IrO<sub>x</sub>-NDs.



Fig. 2 Charge trapping behavior of  $IrO_x$  NDs by fabricating as flash memory device in an  $IrO_x/Al_2O_3/IrO_x$ -NDs/Al\_2O\_3/SiO\_2 /n-Si structure.



Fig. 3 EDX spectrum of  $IrO_x$  NDs deposited on the SiO<sub>2</sub> surface.



Fig. 4 EDX depth profile of  $IrO_x$  nanodots deposited on the  $SiO_2$  surface.



Fig. 5 XPS analysis of O1s signal of as-deposited  $IrO_x$  nanodots.



Fig. 6 XPS analysis of as-deposited  $IrO_x$  nanodots confirms the formation of respective oxides.



Fig. 9 Comparative sensitivity of bare  $SiO_2$  and  $IrO_x$  nanodots modified EIS sensor.



Fig. 7 The C-V curve of bare  $SiO_2$  sensor in different pH buffer solutions.



Fig. 10 Standard error measurement from the three successive  $IrO_x$  modified EIS sensor.



Fig. 8 The CV curve of IrO<sub>x</sub> nanodots modified EIS sensor.



Fig. 11 Concap response of  $IrO_x$  modified EIS sensor.